

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Jaime Poris
Assignee: Nanometrics Incorporated
Title: Method of Measuring Dishing
Serial No.: 09/578,798 Filing Date: May 23, 2000
Examiner: William C. Choi Group Art Unit: 2873
Docket No.: NAN040 US Confirmation No: 5190

Santa Clara, California
March 24, 2003

COMMISSIONER FOR PATENTS
Washington, D. C. 20231

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.97(c)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, §1.97 and §1.98, the Applicants submit for consideration in the above-identified patent application the documents listed on the accompanying Form PTO-1449. A copy of the documents is also submitted herewith. The Examiner is requested to make this document of record.

This Information Disclosure Statement is submitted pursuant to 37 CFR §1.97(c) as it is after receipt of a first Office Action on the merits but before mailing of a final Action or Notice of Allowance. Accordingly, a fee is required pursuant to 37 CFR §1.17(p). A Fee Transmittal form (PTO/SB/17) is attached to this submission.

The attached Form PTO-1449 lists references 3 through 7. Applicants would appreciate the Examiner initialing and returning the Form PTO-1449, indicating that the information has been considered and made of record herein.

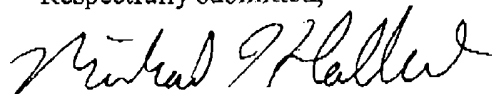
The information contained in this Information Disclosure Statement under 37 C.F.R. §1.555 is to the best of my knowledge and is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the examination of this application does not exist; (iii) the information, protocols, results and the

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like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

Via Express Mail Label No.
EU 227 021 194 US

Respectfully submitted,



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Sheet 1 of 1

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|--|----|--|-----------------|-----------------------|-------|-----------------|----------------------------|
| U.S. Department of Commerce, Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary) | | | | Application No.: | | 09/578,798 | |
| | | | | Filing Date: | | May 23, 2000 | |
| | | | | First Named Inventor: | | Jaime Poris | |
| | | | | Group Art Unit: | | 2873 | |
| | | | | Examiner Name: | | William C. Choi | |
| | | | | Confirmation No.: | | 5190 | |
| | | | | Attorney Docket No.: | | NAN040 US | |
| U.S. Patent Documents | | | | | | | |
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
| | 3. | 5,348,002 | 9/20/94 | Caro | 128 | 633 | |
| | 4. | 5,555,471 | Sep/10/96 | Xu et al. | 356 | 357 | |
| | 5. | 5,914,782 | Jun/22/99 | Sugiyama | 356 | 351 | |
| | 6. | 6,392,752 | 5/21/02 | Johnson | 356 | 511 | |
| OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | 7. | Stine, B. et al., "Rapid Characterization and Modeling of Pattern-Dependent Variation in Chemical-Mechanical Polishing", IEEE Transactions on Semiconductor Manufacturing, Vol. 11, No. 1, pp. 129-140 (Feb. 1998) | | | | | |
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| Examiner | | | Date Considered | | | | |
| *EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant. | | | | | | | |